



635.43483X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: S. KADLEC, et al.
Serial No: 10/798,331
Filed: March 12, 2004
Title: METHOD FOR MANUFACTURING SPUTTER-COATED
SUBSTRATES, MAGNETRON SOURCE AND SPUTTERING
CHAMBER WITH SUCH SOURCE
Group: 1795
Examiner: Michael A. Band
Conf. No.: 6134

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

August 28, 2008

Sir:

In response to the Office Action dated February 28, 2008, please
amend the above-identified application as listed below and as set forth on the
following pages:

Amendments to the Claims

Amendments to the Drawings describing changes to drawings shown
in the Appendix

Remarks are included following the amendments

An Appendix including an amended drawing figure is attached following
the Remarks.